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## AMENDMENTS TO THE CLAIMS

This listing will replace all prior versions, and listings, of claims in the application.

Listing of Claims

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- 1. 28 (Canceled).
- 29. (Original) A method of applying an elongate member to a substrate, the method comprising the steps of:

moving the substrate in a flow direction thereof;

feeding the elongate member to a guide capable of guiding the elongate member onto the substrate along a securement path, the guide being supported by a guide assembly for conjoint lateral movement therewith relative to the flow direction of the substrate;

moving the guide assembly laterally relative to the flow direction of the substrate so that at least a portion of the securement path extends generally oblique to the flow direction of the substrate;

moving the guide relative to the guide assembly to vary the position of the elongate member transversely within the securement path as the elongate member is guided onto the substrate; and

securing the elongate member to the substrate.

- 30. (Original) A method as set forth in claim 29 wherein said guide moving step comprises moving the guide relative to the guide assembly to guide the elongate member onto the substrate generally in a periodic wave pattern within the securement path.
  - 31. 34. (Canceled).

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- 35. (New) The method set forth in claim 29 wherein the step of moving the guide assembly laterally relative to the flow direction of the substrate comprises moving the guide assembly along a generally arcuate path relative to the flow direction of the substrate whereby a component of said arcuate path extends laterally relative to said flow direction of the substrate.
  - 36. (New) The method set forth in claim 35 wherein the guide assembly has a positioning arm adapted for pivoting movement relative to the flow direction of the substrate about a rotation axis of the positioning arm, the guide being supported by the positioning arm in radially spaced relation with the rotation axis of the positioning arm such that pivoting movement of the positioning arm laterally positions the guide relative to the flow direction of the substrate, the step of moving the guide assembly along an arcuate path comprising pivoting the positioning arm about its rotation axis to move the guide laterally relative to the flow direction of the substrate.
  - 37. (New) The method set forth in claim 29 where the guide is a first guide capable of guiding a first elongate member onto the substrate along a securement path, the method further comprising:
  - feeding a second elongate member to a second guide capable of guiding the second elongate member onto the substrate along the securement path, the second guide being supported by the guide assembly for conjoint lateral movement therewith relative to the flow direction of the substrate;
- moving the second guide assembly laterally relative to the flow direction of the substrate so that the second elongate

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member extends along the securement path;

moving the second guide relative to the guide assembly to vary the position of the second elongate member transversely within the securement path as the second elongate member is guided onto the substrate; and

securing the second elongate member to the substrate.

- 38. (New) The method set forth in claim 37 wherein the steps of moving the first guide relative to the guide assembly and moving the second guide relative to the guide assembly comprising moving said first and second guides relative to the guide assembly to guide the elongate members onto the substrate such that the elongate members cross each other at least once along said securement path.
- 39. (New) The method set forth in claim 37 wherein the step of moving the first guide relative to the guide assembly comprises moving the first guide relative to the guide assembly to guide the first elongate member onto the substrate in a generally periodic wave pattern with the securement path whereby at least one period of said periodic wave pattern is defined within said securement path.
- 40. (New) The method set forth in claim 39 wherein the step of moving the second guide relative to the guide assembly comprises moving the second guide relative to the guide assembly to guide the second elongate member onto the substrate in a generally periodic wave pattern with the securement path whereby at least one period of said periodic wave pattern is defined within said securement path.
- 41. (New) The method set forth in claim 40 wherein the periodic wave pattern of the first elongate member is different

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from the periodic wave pattern of the second elongate member such that the spacing between the elongate members varies along said securement path.

- 42. (New) The method set forth in claim 41 wherein the periodic wave pattern of said first elongate member is the negative of the periodic wave pattern of said second elongate member.
- 43. (New) The method set forth in claim 29 wherein, the guide is supported on the guide assembly for orbiting movement relative to the guide assembly, the step of moving the guide relative to the guide assembly comprising moving the guide relative to the guide assembly through an arc of up to about 360 degrees to vary the position of the guide laterally relative to the flow direction of the substrate.